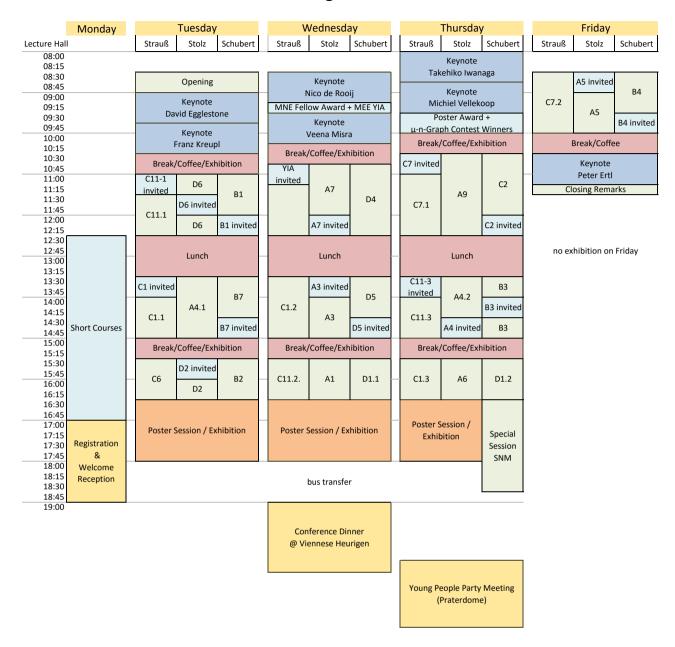
# **Short Program MNE 2016**



## A. Micro- and Nanopatterning

- A1 Photon lithography
- A3 Electron and ion beam lithography
- A4.1 Soft lithography 1
- A4.2 Soft lithography 2
- A5 Materials for micro- and nanolithography
- A6 Directed Self Assembly
- A7 Tip based patterning
- A9 Novel techniques

#### C. Micro/Nano Devices and Systems

- C1.1 MEMS / NEMS 1 actuation
- C1.2 MEMS / NEMS 2 processing
- C1.3 MEMS / NEMS 3 energy harvest
- C2 Micro and nano fluidic systems
- C6 Device and system modelling
- C7.1 Micro / Nano devices for physical science 1
- C7.2 Micro / Nano devices for physical science 2 optical devices
- C11.1 Applications 1 sensors
- C11.2 Applications 2 memory
- C11.3 Applications 3 fabrication

### **B. Micro- and Nanofabrication**

- B1 Pattern transfer
- B2 Plasma etching
- B3 Beam induced deposition and 3D microprinting
- B4 3D nanomanufacturing
- B7 (Nano-) Metrology

#### D. MNE for Life Sciences and Biology

- D1.1 Sensing 1 biomolecules
- D1.2 Sensing 2
- D2 Lab-on-a-Chip
- D4 Micro / Nanofluidics for bio / life sciences
- D5 System design and fabrication
- D6 Applications